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Lin Li
Minghui Hong
Lan Jiang
Editors

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Contents

vii	<i>Authors</i>
ix	<i>Conference Committee</i>
xiii	<i>Introduction</i>

Part A

LASER PROCESSING AND RAPID PROTOTYPING TECHNIQUES

9673 02	Laser sintered thin layer graphene and cubic boron nitride reinforced nickel matrix nanocomposites [9673-102]
9673 03	Simulation and experimental implementation of beam-shaping in a side-pumped Nd:YAG amplifier [9673-103]
9673 04	Effects of activating fluxes on the weld penetration and corrosion resistant property of laser welded joint of ferritic stainless steel [9673-105]
9673 05	Study of laser-induced damage to GaAs/Ge solar cells [9673-106]
9673 06	Study on the activated laser welding of ferritic stainless steel with rare earth elements yttrium [9673-107]
9673 07	Study of application and key technology of the high-energy laser weapon in optoelectronic countermeasure [9673-108]
9673 08	Numerical simulation of heat accumulation effects with different repetition rate pulse laser [9673-109]
9673 09	Filtering method for 3D laser scanning point cloud [9673-110]
9673 0A	Fiber laser cutting of AZ31 magnesium alloy: numerical and experimental investigation [9673-111]

Part B

MICRO/NANO OPTICAL MANUFACTURING TECHNOLOGY

9673 0B	Calibration of the lateral spring constant of atomic force microscope cantilevers [9673-4]
9673 0C	Uniformity of reshaped beam by diffractive optical elements with light-emitted diode illumination [9673-5]

9673 OD	A 4×4 point to point router based on microring resonators [9673-8]
9673 OE	Size effect study of thin film hardness using AFM nanoindentation [9673-20]
9673 OF	Perfect shuffle transform based on subwavelength binary blazed grating [9673-23]
9673 OG	Ultrathin reduced graphene oxide films for high performance optical data storage [9673-25]
9673 OH	Study of the blue-green laser scattering from the rough sea surface with foams by the improved two-scale method [9673-28]
9673 OI	Optimal samples for precision blind tip reconstruction [9673-29]
9673 OJ	Integrated Bragg grating filter in ultra-thin silicon-on-insulator strip waveguides [9673-30]
9673 OK	Research on the implementation method of the fine subdivision of grating sensor signal [9673-33]
9673 OL	Microring resonator optical waveguide gyroscope based on coupling coefficient and coupling area modulating [9673-36]
9673 OM	Chiral metamaterial with VO₂ inclusions for thermally manipulating cross-polarization [9673-38]
9673 ON	A new manufacturing technology of radio telescope panel [9673-42]
9673 OO	Echelle and etalon used for spectral metrology of excimer laser lithographic light sources at 193nm [9673-43]
9673 OP	Interference enhancement and modulation introduced by surface plasmon polaritons in a concentric-ring structure [9673-45]
9673 OQ	A PIV study of light-driven tangential micro flows occurring near a decane-water interface [9673-47]
9673 OR	CUDA-based high-performance computing of the S-BPF algorithm with no-waiting pipelining [9673-48]
9673 OS	Nano-structured silicon surfaces with broadband and wide-angle antireflective properties for solar cells [9673-49]
9673 OT	SERS application of propagating surface plasmon modes in 1D metallic gratings [9673-50]
9673 OU	The Raman spectrum of graphene oxide decorated with different metal nanoparticles [9673-51]
9673 OW	Tunable unidirectional long-range surface plasmon polaritons launching based on nanoslits [9673-56]
9673 OX	Correlation of structural and magnetic properties of ZnO films with different Fe doping concentrations [9673-59]

- 9673 0Y **Size and distribution controllable silica microballs fabricated by electrospraying** [9673-60]
- 9673 0Z **Control of surface ablation on fused silica with ultrafast laser double-pulse based on seed electrons dynamics control** [9673-61]
- 9673 10 **Titanium dioxide thin film deposited on flexible substrate by multi-jet electrospraying** [9673-62]
- 9673 11 **The thermo-optic characteristics of CdSe/ZnS quantum dot with Z-scan measurement method using a CW laser** [9673-67]
- 9673 12 **Improving the measurement accuracy of mixed gas by optimizing carbon nanotube sensor's electrode separation** [9673-70]

Authors

Numbers in the index correspond to the last two digits of the six-digit citation identifier (CID) article numbering system used in Proceedings of SPIE. The first four digits reflect the volume number. Base 36 numbering is employed for the last two digits and indicates the order of articles within the volume. Numbers start with 00, 01, 02, 03, 04, 05, 06, 07, 08, 09, 0A, 0B...0Z, followed by 10-1Z, 20-2Z, etc.

Bai, Lujun, 00	Li, Zhipeng, 0M
Cao, Zhoubin, 10	Li, Zi-zheng, 0S
Chang, Qingmei, 0R	Liu, Bo, 0K
Chang, Shengli, 0L	Liu, Che, 0K
Chen, Dingbo, 0F	Liu, Congcong, 0E
Chen, Jianping, 0J	Liu, Da, 09
Chen, Mengzhu, 0C	Liu, Guangyi, 0O
Chen, Si Fan, 0U	Lu, Huanyu, 0D, 0F
Chen, Yi, 0N	Lu, Jian, 08
Cheng, Cheng, 11	Lu, Yan-qing, 0T
Cui, Nai-Yi, 0Q	Lv, Tingting, 0M
Deng, Lin, 0R	Lyu, Jie, 11
Ding, Yanfei, 0I	Ni, Daihong, 10
Fan, Zhongwei, 03	Ni, Xiaowu, 08
Feng, P., 0Z	Peng, Li, 0P
Fu, Xing, 0B	Qi, Xiao, 0H
Gao, Fei, 0O	Qi, Xinghua, 0K
Gao, Haixia, 0K	Qian, Shuangbei, 0E
Gao, Jin-song, 0S	Qin, Kang, 0T
Ge, Jianquan, 0X	Qiu, Min, 0W
Gu, Huarong, 0C	Qu, Zhou, 07
Gu, Wenhua, 0P, 0Y, 10	Quan, Long, 12
Guo, Huafeng, 0A	Ran, P., 0Z
Guo, Shijia, 0E	Ren, Guangsen, 05
Guo, Yuye, 0I	Rong, W. L., 0Z
Han, Bing, 08	Shen, Junqi, 04, 06
Han, Xiang'e, 0H	Shen, Zhonghua, 08
Han, Yu, 0R	Shi, Jinhui, 0M
Hao, Huimin, 12	Shi, Quanchao, 0M
Hao, Yuncai, 09	Song, Yunpeng, 0B
He, Min, 0A	Su, Hao-ran, 0T
Hu, Shengsun, 04, 06	Sun, Bo, 0M
Hu, Xiaodong, 0E, 0I	Sun, Tao, 0A
Hu, Zengrong, 02	Tan, Qiaofeng, 0C
Huang, Di, 0E	Tong, Guoquan, 02
Huang, Jie, 0D, 0F, 0L	Wan, Jiahuan, 0I
Huang, Ke, 03	Wan, Xuexiang, 0Q
Jiang, Qi, 0Y	Wang, Dawei, 07
Lai, Senfeng, 0P	Wang, Lei, 0X
Li, B., 0Z	Wang, Li, 09
Li, Irene Ling, 0U	Wang, Qian, 0O
Li, Juan, 0E	Wang, Qian-jin, 0T
Li, Juli, 0A	Wang, Qiugui, 07
Li, Lei, 0R	Wang, Qixia, 0C
Li, Pengzhi, 0N	Wang, Yanbin, 05
Li, Qiang, 0W	Wang, Yonghui, 04, 06
Li, X., 0Z	Wu, Pan, 0Y
Li, Xiangzhen, 0H	Wu, Sen, 0B, 0E, 0I
Li, Zewen, 08	Wu, Wen, 0P

Wu, Wenjun, 0D, 0F, 0L
 Wu, Xiao, 0A
 Xi, Xiaoqi, 0R
 Xia, Na, 0W
 Xiao, Hong, 03
 Xie, Yu-bo, 0T
 Xing, Fei, 0G
 Xing, Hao, 07
 Xu, Bojing, 0Y
 Xu, Linyan, 0B, 0E, 0I
 Xu, Su, 0T
 Xu, Suzhi, 0F
 Xu, Wei, 0X
 Yan, Bin, 0R
 Yan, Jinhua, 11
 Yang, Hai-gui, 0S
 Yang, Junbo, 0D, 0F, 0L
 Yang, Q. Q., 0Z
 Yang, Tao, 0X
 Yang, Yong, 0G
 Yang, Yuanjie, 0D
 Yang, Yuanqing, 0W
 Yi, Wuming, 10
 Yuan, Xiaocong, 0G
 Zhai, Jian Pang, 0U
 Zhang, Fan, 0Q
 Zhang, Hailiang, 0L
 Zhang, Hang, 11
 Zhang, Jingjing, 0D, 0F, 0L
 Zhang, Jun, 09
 Zhang, K. H., 0Z
 Zhang, Wenpan, 05
 Zhang, Xiang, 0R
 Zhang, Xue-jin, 0T
 Zhang, Yong, 12
 Zhao, Jiangshan, 0O
 Zhao, Tianzhuo, 03
 Zhou, Jie, 08
 Zhou, Linjie, 0J
 Zhu, Rongzhen, 05
 Zhu, Siwei, 0G
 Zhu, Yong-yuan, 0T
 Zou, Zhi, 0J

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Introduction

Applied Optics and Photonics, China (AOPC2015) is the annual conference of the Chinese Society for Optical Engineering, and it is also the largest academic and industrial event in the field of optical and optoelectronic technology in China. The AOPC2015 organization committee intended to build a cohesive platform for academic exchanges, industry exhibitions, and corporate negotiations. The conference had 7 themes, which included 22 technical conferences and 600 technical presentations. We sincerely hope that the research and development of optoelectronic technology was promoted, and that the international cooperation of the optical and optoelectronic industry was enhanced.

AOPC2015 was sponsored by the Chinese Society for Optical Engineering; SPIE, the Optical Society, the European Optical Society, and the Optical Society of Korea were technical co-sponsors. There were also 28 cooperating organizations that supported the conference. We received a total of 1,219 contributions from more than 15 countries, including: the United States, the United Kingdom, Germany, France, Spain, Australia, Canada, Mexico, Brazil, Japan, Republic of Korea, Thailand, Singapore, Russian Federation, and China. Nearly 700 submissions were accepted for the *Proceedings of SPIE*, and over 150 invited talks and papers were suggested to be published in Journals indexed by SCI and Ei. After careful discussion, we selected five plenary speeches, which were presented by famous scientists from the United States, the United Kingdom, Republic of Korea, Japan, and China. There were 205 invited talks in 12 of the technical conferences. On behalf of the organization committee of AOPC, I express thanks to all of the invited speakers and authors for their contributions to and support of the conference.

To celebrate the International Year of Light 2015, we set up 12 display boards highlighting IYL in the exhibition area on the first level. These display boards were to educate the public about light and the applications of light in society.

Finally, on behalf of Prof. Songlin Zhuang, the other co-chairs, and the organization committee of AOPC, I would like to heartily thank our sponsors and cooperating organizations for all they have done for the conference. I thank all of the participants and friends for their interest and efforts in helping us make the conference a success. I also thank the program committee for their effective work and valuable advice—especially the AOPC2015 secretariat and the SPIE staff for their tireless effort and outstanding services in preparing the conference and publishing the proceedings.

Again, we extend our warmest greetings to you and hope you had a pleasant and exciting stay in Beijing!

Guofan Jin